



SHEET 1 OF 1

INFORMATION DISCLOSURE CITATION IN AN APPLICATION (PTO-1449)				ATTY. DOCKET NO. 55071-268	SERIAL NO. 10/626,864	
				APPLICANT Xuelong SHI, et al.		
				FILING DATE July 25, 2003	GROUP 2825	
U.S. PATENT DOCUMENTS						
EXAMINER'S INITIALS	CITE NO.	Document Number Number-Kind Code ² (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	
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EXAMINER'S INITIALS	CITE NO.	Foreign Patent Document Country Codes - Number - Kind Codes (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines Where Relevant Figures Appear	Translation
NL		WO 99/14638	03/25/1999	NUMERICAL TECHNOLOGIES, INC.		Yes No
						x
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)						
EXAMINER'S INITIALS	CITE NO.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.				
NL		HEWAK, Daniel, et al. "Fabrication of tapers and lenslike waveguides by a microcontrolled dip coating procedure." Applied Optics, Volume 27, Number 21, November 1, 1988, pp. 4562-4564				
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EXAMINER Nam			DATE CONSIDERED 11/21/05			

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